



1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Helmut Wurzer et al.

Art Unit : 1763

Serial No. : 09/882,289

Examiner : George A. Goudreau

Filed : June 15, 2001

Title : METHOD FOR FABRICATING A BARRIER LAYER

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

#15
#7/11/03
MW

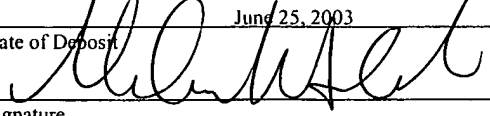
RESPONSE TO RESTRICTION REQUIREMENT

Responsive to the action mailed June 2, 2003, applicant previously elected the invention of Group I (claims 8 to 15) drawn to a method for making a semiconductor comprised of first oxidizing the Si based substrate followed by second treating the substrate to form an oxygen impervious layer between the oxide layer, and the Si based substrate. Applicant further elects claim 12 (selecting the substrate-nitrogen compound to include silicon nitride) and claim 14 (etching the substrate oxide layer in a wet-chemical process) and withdraws claims 13 and 15. The election is made without traverse.

RECEIVED
JUL 01 2003
TC 1700

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date of Deposit June 25, 2003

Signature

Melissa K. Addis
Typed or Printed Name of Person Signing Certificate


Applicant : Helmut Wurzer et al.
Serial No. : 09/882,289
Filed : June 15, 2001
Page : 2

Attorney's Docket No.: 12816-018001 / S1187 SB

No fee is believed to be due at this time; however, if any fees are due please apply any charges to Deposit Account No. 06-1050 referencing attorney docket number 12816-018001.

Respectfully submitted,

Date: June 25, 2002


Faustino A. Lichauco
Reg. No. 41,942

Fish & Richardson P.C.
225 Franklin Street
Boston, Massachusetts 02110-2804
Telephone: (617) 542-5070
Facsimile: (617) 542-8906

20680447.doc